a slit provided in [the] an optical path between said objective lens and said light detection means; and

illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to switch over bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured.

3. (Twice Amended) [A] The surface compression apparatus described in claim 1, [characterized in that the] wherein a size of an opening of said slit is changeable.

4. (Twice Amended) [A] The surface inspection apparatus described in claim 1, [characterized in that] wherein said light detection means comprises calculation means for converting [the] said light quantity of [the] said light having passed through said slit [on the basis of] based upon a light quantity detected when a standard sample is used as [said] the object to be measured.

5. (Amended) A surface inspection method [characterized in that] comprising the steps of:

irradiating a surface of an object to be measured [is irradiated] with an irradiation light [and the] , said irradiation light [is] being reflected [on] from a light source onto the surface of [said] the object to be measured[,] to form a reflected light;

[in this reflected light,] making a component of said reflected light, parallel with [the] an optical axis of an objective lens provided oppositely to [said] the object to be measured, [is made] incident on a slit through said objective lens[,] to form an incident light;

switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and a dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured;

[in this incident light,] receiving only a component of said incident light having passed through an opening of said slit [is received,] to form a received light; and

[the] obtaining a light quantity of [this] said received light[is obtained].

6. (Amended) [A] The surface inspection method described in claim 5, [characterized in that] further comprising controlling a light detection extent in the surface of [said] the object to be measured [is controlled] by changing [the] a size of [the] said opening of said slit and [the] a magnification of said objective lens[, respectively].

7. (Twice Amended) [A] The surface inspection method described in claim 5, [characterized in that the] further comprising converting said light quantity of said received light [on the basis of] based upon a light quantity detected when a standard sample is used as [said] the object to be measured.

8. (Amended) [A] The surface inspection method described in claim 7, [characterized in that the] further comprising varying an irradiation angle with [the] said

irradiation light to [said] the object to be measured [is varied] according to [the] a surface condition of [said] the object to be measured.

9. (Amended) A surface inspection apparatus [characterized by] comprising:

a light source for applying a light to a surface of an object to be measured[,];

a tubular member opposite to the surface of [said] the object to be measured and for receiving said light applied from said light source and reflected on the surface of [said] the object to be measured[,] to become a reflected light;

light detection means for detecting a component incident on [this] said tubular member from a specified direction in [the] said reflected light and obtaining [its] a light quantity thereof[, and];

a slit provided in [the] an optical path between said tubular member and said light detection means; and

illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to switch over bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured.

10. (Amended) [A] The surface inspection apparatus described in claim [1] 9, [characterized in that the] wherein said tubular member is an optical fiber cable.

11. (Amended) A surface inspection method [characterized in that] comprising the steps of:

irradiating a surface of an object to be measured [is irradiated] with a light [and the] to form an irradiation light;

reflecting said irradiation light [is reflected] on the surface of [said] the object to be measured[,] to form a reflected light;

[in this reflected light,] making only a component in almost one direction [is made] incident on a slit through [the] a tubular member[,] in the reflected light to form an incident light;

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switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and a dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured; and

[in this incident light, the] obtaining only a component of a light quantity [of only a component having passed] through an opening of said slit [is obtained] in said incident light.

12. (Amended) A surface inspection method [characterized in that] comprising the steps of:

irradiating a surface of an object to be measured [is irradiated] with a light [and the] to form an irradiation light;

reflecting said irradiation light [is reflected] on the surface of [said] the object to be measured[,] to form a reflected light;

[is made] making said reflected light incident on a slit through an optical fiber cable[,] to form an incident light;

switching over an illumination switchover means provided in a light path between said light source and the object to be measured, wherein said illumination switchover means is structurally configured to be switched over between a bright-field illumination, using a half-mirror portion, in which said light from said light source is made parallel with said optical axis of said objective lens and applied to the object to be measured through said objective lens, and a dark-field illumination, in which said light from said light source is made ringlike and applied obliquely with respect to said optical axis of said objective lens such that there is a focus on the surface of the object to be measured; and

[, in this incident light, the] obtaining a light quantity of only a component having passed through an opening of said slit [is obtained] in said incident light.

13. (Amended) [A] The surface inspection apparatus described in claim [2] 1, [characterized in that the] wherein a size of an opening of said slit is changeable.

14. (Amended) [A] The surface inspection apparatus described in claim [2] 1, [characterized in that] wherein said light detection means comprises calculation means for converting [the] said light quantity of [the] said reflected light having passed through said slit [on the basis of] based upon a light quantity detected when a standard sample is used as [said] the object to be measured.

15. (Amended) [A] The surface inspection apparatus described in claim 3, [characterized in that the] wherein said light detection means comprises calculation means for converting [the] said light quantity of [the] said reflected light having passed through said slit [on the basis of] based upon a light quantity detected when a standard sample is used as [said] the object to be measured.